

Electronic Patent Application Fee Transmittal

Application Number:	09605293			
Filing Date:	28-Jun-2000			
Title of Invention:	METHOD FOR CONTROLLING THE MORPHOLOGY OF DEPOSITED SILICON ON A SILICON DIOXIDE SUBSTRATE AND SEMICONDUCTOR DEVICES INCORPORATING SUCH DEPOSITED SILICON			
First Named Inventor/Applicant Name:	DAVID L. CHAPEK			
Filer:	Mark S. Matkin/Lori Tetrault			
Attorney Docket Number:	MI22-4201			
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Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
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Submission- Information Disclosure Stmt	1806	1	180	180
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